

PATENT ABSTRACTS OF JAPAN

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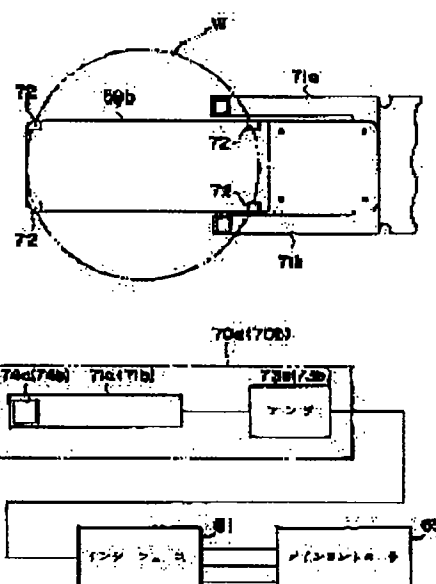
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(54) SUBSTRATE CONVEYER

(57)Abstract:

PURPOSE: To elevate the accuracy of the automatic teaching and enable the existence of a substrate and the recognition of the positional relation between the substrate and fork by detecting the distance between the substrate and contactless sensors fixed to both sides of the fork so as to be movable together with the fork and the position of the substrate in a horizontal plane.

CONSTITUTION: Contactless capacitance sensors 70a and 70b composed of sensor heads 71a and 71b fixed to both sides of a fork 59b and amplifiers 73a and 73b connected to the heads machine the capacitances between a wafer W and sensor units 74a and 74b located at their top ends and output signals corresponding to the distances from the amplifiers 73 according to the capacitances. An interface 81 interprets the output distance signals from the amplifiers 73 according to previously given values to output the existence of the wafer W, the distance between the wafer and fork and information for the automatic teaching to a main controller.



LEGAL STATUS

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